

**AMENDMENTS TO THE CLAIMS:**

This listing of claims will replace all prior versions, and listings, of claims in the application:

1. (Canceled)

2. (Previously Presented) An electrolytic polishing apparatus for electrolytic-polishing a conductive film formed on a substrate, comprising:

a resistance measuring unit for measuring electric resistance of said conductive film and a etching stopper film formed on said substrate, and further comprising a termination point detecting unit for detecting a termination point of polishing by reading a variation resistance value of said conductive film and said etching stopper film measured by said resistance measuring unit.

3. (Canceled)

4. (Canceled)

5. (Canceled)

6. (Canceled)

7. (Canceled)

8. (Canceled)

9. (Canceled)

10. (Canceled)

Please add the following new claims: